WHAT IS CLAIMED IS:

1	1. An apparatus for forming a pattern on a surface of a
2	substrate comprising:
3	a probe chip, said probe chip comprising a plurality of
4	probes arranged in an array along said probe chip, the array being one of one-
5	dimensional and two-dimensional, each of said plurality of probes having a tip;
6	a first actuator for moving the probe chip parallel to the
7	surface of the substrate;
8	said probe chip further comprising a plurality of second
9	actuators operatively connected to each of the plurality of probes, for
10	selectively raising or lowering the tip of each of the probes in a direction
11	substantially perpendicular to the surface of the substrate;
12	a source connected to each of the plurality of second
13	actuators for selectively actuating the plurality of second actuators.
14	
15	2. The apparatus of claim 1 wherein each of said second
16	actuators is configured to move the tip of a selected probe away from the
17	substrate upon actuation of a selected second actuator.
18	
19	3. A substrate having a pattern of a patterning compound on
20	its surface, said pattern being produced by a method comprising the steps of:

21	moving a chip over the substrate to position a plurality of
22	probes over said substrate simultaneously;
23	selectively actuating at least one of the plurality of probes
24	to place the probes in one of in contact and out of contact of the substrate,
25	while at least another of the plurality of probes remains out of contact with the
26	substrate; at least the plurality of probes placed in contact with the substrate
27	having a tip and the patterning compound on the tip;
28	wherein the pattern is formed by application of the
29	patterning compound from the tip to the substrate.
30	
31	4. The substrate of claim 3 wherein the patterning compound
32	comprises a biological compound.
33	
34	5. The substrate of claim 3 wherein, when the at least one of
35	the probes is placed in contact with the substrate, the tip of each of the in-
36	contact probes is within a sufficient distance of the substrate to permit
37	patterning of the patterning compound.
38	
39	6. The substrate of claim 3 wherein the patterning compound
40	comprises at least two different types of patterning compounds.
41	
42	7. The substrate of claim 3 wherein the substrate is a
43	patterned integrated circuit.

44	8.	The substrate of claim 3 wherein the patterning compound
45	comprises at leas	t one of octadecanethiol (ODT)and mercaptohexadecanoic
46	acid (MHA).	
47		
48	9.	The substrate of claim 3 wherein lines are formed by
49	selected probes in	contact with the substrate, the lines being less than 100 nm
50	in width.	
51		
52	10.	The substrate of claim 3, wherein the substrate comprises
5 3	gold.	
54		
55	11.	An apparatus for applying a patterning compound to a
56	substrate for nano	lithography, the apparatus comprising:
57		a plurality of scanning probe microscope (SPM)
58	instrument probes	arranged in an array;
59		an actuator operatively connected to each of the plurality
60	of AFM probes for	or selectively actuating each of the probes, thus placing a tip
61	of each of the	selectively actuated probes in sufficient proximity to the
62	substrate to allow	application of the patterning compound thereto.
63		
64	12.	The apparatus of claim 11 wherein the plurality of SPM
65	probes are dispose	ed on a probe chip.
66		

67	13.	The apparatus of claim 12 further comprising:
68		a scanner tube for moving the probe chip.
69		
70	14.	The apparatus of claim 13 wherein the scanner tube uses
71	piezo-actuation.	
72		
73		